Temperature-Aware and Low-Power Design and Synthesis of Integrated Circuits and Systems

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#### Introduction

Forced air and heatsinks Alternative technologies Solid State

# Outline

### 1. Introduction

2. Forced air and heatsinks

3. Alternative technologies

4. Solid State

Solid State

# Introduction

- Cooling fundamentals
- Multiple cooling methods
  - Combinations often used in real applications

# Multiple modes common in real applications



#### Introduction

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# Conduction

$$P = A\kappa \cdot \Delta T/d$$

- P: Power in W
- A: Area
- $\kappa$ : Thermal conductivity
- $\Delta T$ : Difference in temperature
- *d*: Depth

# Radiative cooling

### $P = Ae\sigma T^4 - Ae\sigma T^4_A$

- P: Power in W
- A: Surface area
- e: Emissivity of surface [0:1]
  - 0.3 for Cu, 0 for rough black surface
- $\sigma$ : Stefan-Boltzmann constant = 5.67×10<sup>-8</sup> W/(m<sup>2</sup> K)
- T: Temperature
- T<sub>A</sub>: Ambient temperature
- Why does a thermos have mirrored walls?

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# Radiative interaction

$$k = \frac{A\cos\theta}{4\pi r^2}$$

- k: Patch interaction coefficient
- A: Patch area
- $\theta$ : Angle between patches
- r: Distance between patches

## Other uses of radiation



Radiosity



Ray tracing

# Convection

Convection:

$$P = 2hA(T_S - T_F)$$
  
 $h \approx k_1(T_S - T_F)^{1/4}$ 

Therefore,

$$I \propto (T_S - T_F)^{5/4}$$

- P: Power in W
- h: Heat transfer coefficient
- k<sub>1</sub>: Constant for film coefficient and film conductance (0.0021 W/(m<sup>2</sup> K))
- A: Area of one side of plate
- $T_S$  and  $T_F$ : Solid and fluid temperatures

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# Forced air heatsink

How to improve?

- Increase fluid flow rate, decreasing surface film thickness
- Or increase film conductance
  - Increases k<sub>1</sub>
- Increase surface area
- Increase temperature difference (?)
- Increase conductance to heatsink

## Thermal compounds



Thermal compound performance comparison

#### Credit to Dan's Data and Vegemite.

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# Heatsink attachment



- IBM proposes cutting tree-structure trenches in chip cap
- Thinner interface material, less pressure, few details

# Heatsink attachment



#### Image credit to IBM.

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# lon pump cooling



### Image credit to N. Jewell-Larsen.

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# lon pump operation

- High-voltage positive electrode ionizes air
- lons travel to negative electrode (chip)
- Air pulled along
- Cooled a few mm<sup>2</sup> by  $25 \,^{\circ}$ C this way
- Claiming  $180 \text{ W/(mm^2 K)}$  at 4.5 kV, 2 mm<sup>2</sup>

# Liquid cooling

- Specific heat capacity of water  $4 \times$  air
- Thermal conductivity  $25 \times$  air
- Passive: Vat of oil
- Active: Recirculating pump
  - Where does heat go?
- Microchannel

# Microchannel



#### Image credit to Cooligy.

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# Phase change

- Abrupt change in heat capacity
- Result in transfer in large amount of energy
  - Rate bound results in mixed state
- Latent heat: Amount of energy released or absorbed during evaporation
- $\bullet~855~J/g$  for ethyl alcohol at  $78\,^{\circ}\text{C}$
- 1086 J/g for methyl alcohol at 65  $^{\circ}\text{C}$
- 2258 J/g for water at 100  $^{\circ}\text{C}$

# Heat pipe



#### Heat pipe thermal cycle

- 1) Working fluid evaporates to vapour absorbing thermal energy.
- 2) Vapour migrates along cavity to lower temperature end.
- Vapour condenses back to fluid and is absorbed by the wick, releasing thermal energy
- 4) Working fluid flows back to higher temperature end.

# Electrowetting



Credit to M. G. Pollack for image.

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# Electrowetting

$$\gamma_{SL} = \gamma_{SL}^0 - \frac{\epsilon V^2}{2 \cdot d}$$

- $\gamma_{SL}$ : Solid-liquid interfacial tension
- V applied voltage
- $\gamma_{SL}^0$ : Solid-liquid interfacial tension at V = 0
- $\epsilon$ : Dielectric constant for insulating film
- d: thickness of insulating film

## Electrowetting microactuator



#### Credit to M. G. Pollack for image.

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# Electrical and thermal fields

$$ec{J_Q} =^+ \kappa ec{G}$$
  
 $ec{J_e} = \delta ec{E}$ 

- $\vec{J_Q}$ : Heat flow
- $\kappa$ : Thermal conductivity
- $\vec{G}$ : Temperature gradient
- $\vec{J}_e$ : Electrical current
- $\delta$ : Electrical conductivity
- $\vec{E}$ : Electric potential gradient

Credit to Prof. Grayson for his notes on this topic.

### Thermoelectric interdependence

In the same electric field, hot electrons travel faster than cold electrons inducing heat flow

$$\vec{J_Q} = D\vec{E}$$

Charge flows faster from hot regions to cold regions  $\vec{J_e} = C\vec{G}$ 

# Themroelectric effects

$$\vec{J_e} = \delta \vec{E} + C \vec{G}$$
$$\vec{J_Q} = \kappa \vec{G} + D \vec{E}$$
$$D = CT$$

where T is temperature.

# Themroelectric devices

### Solve for $\vec{E}$ and $\vec{J}_Q$

$$ec{E} = ec{J_e}/\delta - Sec{G}$$
  
 $ec{J_Q} = \pi ec{J_e} + (\kappa - \delta S \pi)ec{G}$   
 $\pi = ST$ 

### Peltier effect

$$ec{J_Q} = \pi ec{J_e} \Rightarrow ec{I_Q} = \pi ec{I_e}$$

where  $I_q$  is the total heat current and  $I_e$  is the total electrical current. Within a piece of metal

$$I_Q^{in} = I_Q^{out} = \pi I_e$$

However, at junction

$$I_Q^{in}-I_Q^{out}=(\pi_A-\pi_B)I_e$$

Thus heat can be transported from one junction to another via charge carriers.

# Peltier heat pumps



## Peltier heat pumps



Schematic of a Thermoelectric Cooler

#### Credit for image to TE Technology, Inc.

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## Stacked Peltier



#### Credit for image to TE Technology, Inc.